Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-341001	Application No. 10/795,808
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR 1.98(b))		Applicant Peter de Groot et al.	
		Filing Date March 8, 2004	Group Art Unit 2877

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Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
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Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation Yes	Translation No
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	CI	Kieran G. Larkin, "Efficient nonlinear algorithm for envelope detection in white light interferometry", J. Opt. Soc. Am A4, pp. 832-843 (1996)
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	CR	A.V. Oppenheim et al., "10.3: The time-dependent Fourier Transform", Discrete-Time Signal Processing, 2nd Edition, pp. 714-722 (Prentice Hall, New Jersey, 1999)
	CS	M.C. Park et al., "Direct quadratic polynomial fitting for fringe peak detection of white light scanning interferograms", Opt. Eng, 39(4), pp. 952-959 (2000)
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	DJ	

Examiner Signature /Michael A. Lyons/	Date Considered 05/12/2006

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